Fig. 1

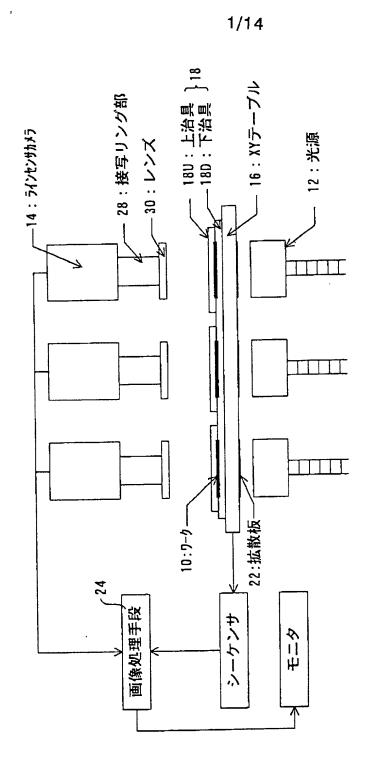
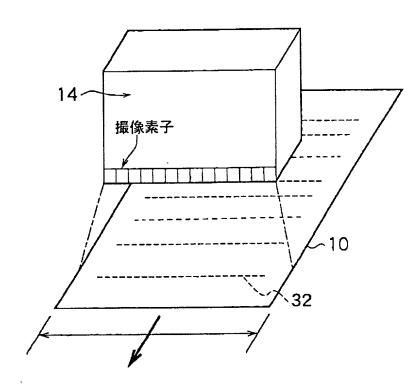


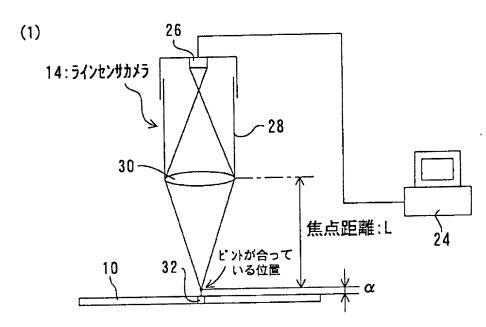
Fig. 2 2/14 16:XYŦ-7' 1 - 14:5インセンサカメラ 20



. :}

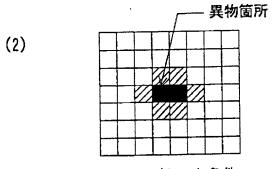






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ピルをずらした状態(ワ-ク表面+α)

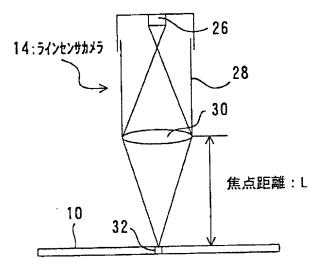


ピントをぼかした条件 (異物サイズ:8画素)

Fig. 5

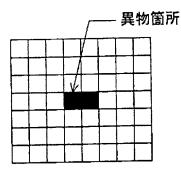
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(1)



ピントを合せた状態(ワーク表面)

(2)

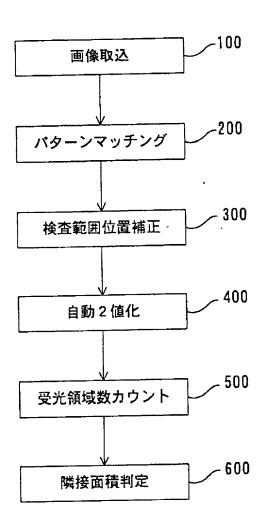


ピントを合わせた条件 (異物サイズ:2画素)

. 1

Fig. 6

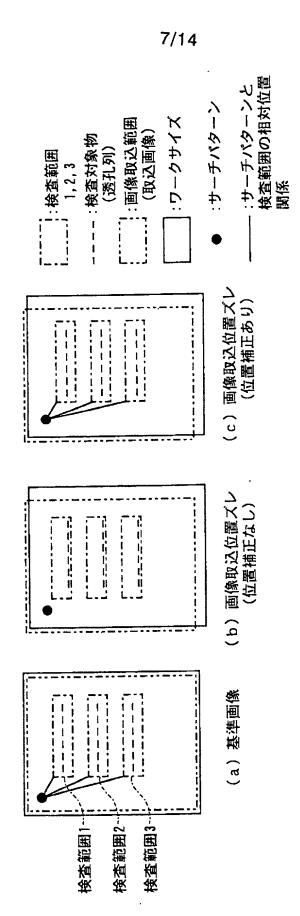
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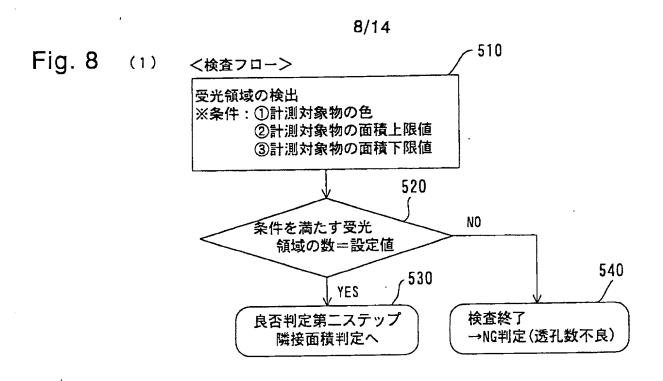


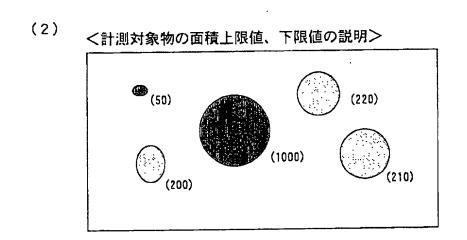
4 ( )

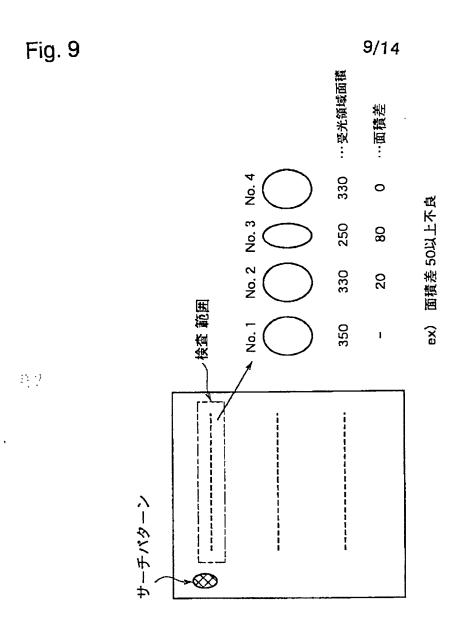
: ';

Fig. 7









4

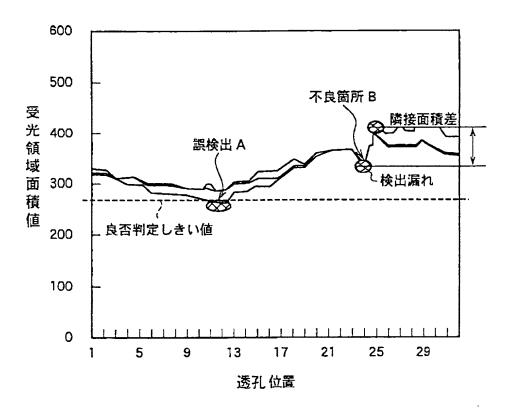
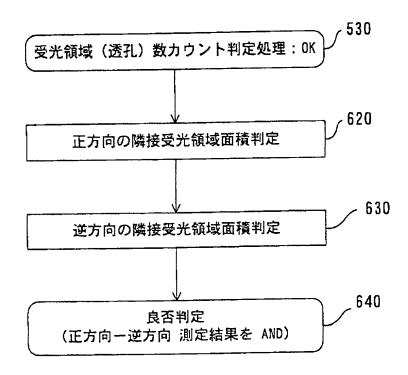


Fig. 11

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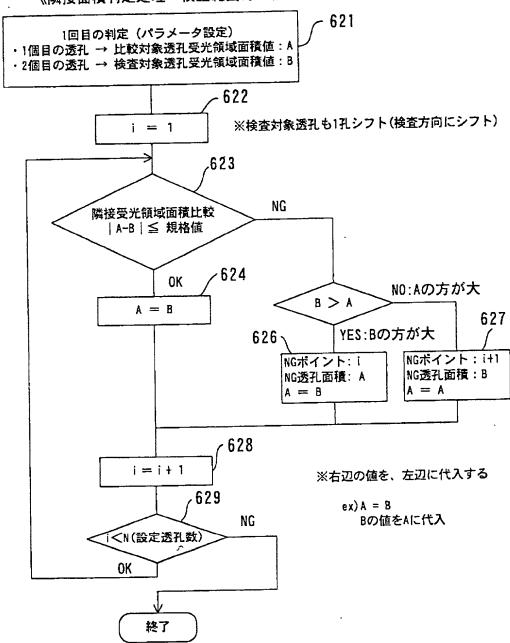
## 《隣接面積判定の流れ》



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Fig. 12

## 《隣接面積判定処理・検査範囲毎の検査フロー》



**蒙**)

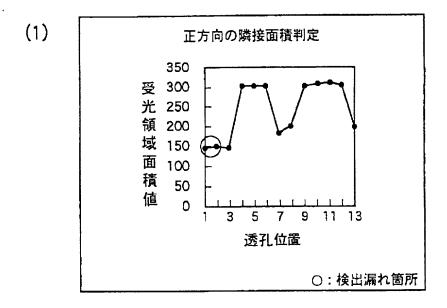
<u>\$</u>`)

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Fig. 13

 $\xi = \tau$ 

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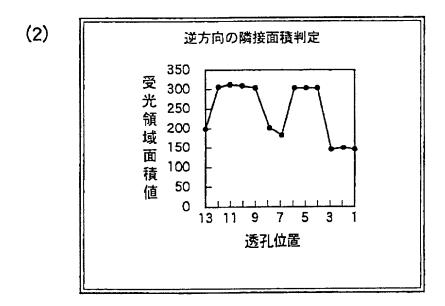


Fig. 14

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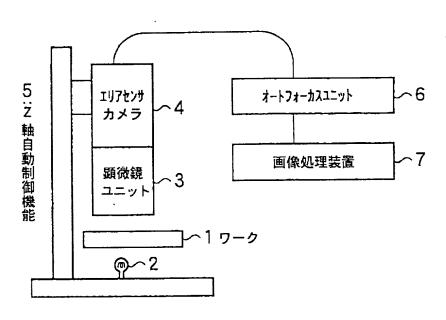


Fig.15

33.3

